

	Type	L #	Hits	Search Text	DBs
1	BRS	L1	497	vacuum and ((substrate wafer) adj handling) and (mask reticle)	USPAT; US-PGPUB
2	BRS	L2	177	1 and lithography	USPAT; US-PGPUB
3	BRS	L3	59	2 and arm	USPAT; US-PGPUB